

**Amendment to the Claims:**

Please cancel claims 35-49 and 54-56 without prejudice to pursuing these claims in a divisional, continuation or other application. Following is a listing of the pending claims upon entry of this amendment.

1-49. (Cancelled)

50. (Previously presented) An apparatus for electrically processing a workpiece, comprising:

- a processing vessel having at least one wall and defining a processing space, the processing space being configured to carry a processing fluid, the wall having an upper edge defining a weir over which the processing fluid can flow;

- a workpiece support positioned at least proximate to the processing vessel, the workpiece support being configured to support a workpiece in contact with a processing fluid when the processing vessel carries the processing fluid, the workpiece support further being configured to carry a first electrode;

- a support configured to carry a second electrode in fluid contact with the processing fluid when the processing vessel carries the processing fluid; and

- an exhaust gas conduit positioned in fluid communication with the processing space, wherein a gas path between the weir and the exhaust gas conduit extends upwardly above the weir.

51. (Previously presented) The apparatus of claim 50 wherein the at least one wall is a first wall and the processing vessel includes a first vessel having the first wall, and wherein the processing vessel further includes a second vessel having a second wall disposed outwardly from the first wall, and wherein the exhaust gas conduit is coupled to the second wall, and wherein the apparatus further comprises an

intermediate wall positioned between the first wall and the exhaust gas conduit, the intermediate wall projecting above the upper edge of the first wall.

52. (Previously presented) The apparatus of claim 50 wherein the at least one wall has a first surface facing inwardly toward the processing space and a second surface facing outwardly away from the processing space, the second surface being configured to support an auxiliary electrode.

53. (Previously presented) The apparatus of claim 50 wherein the at least one wall has a first surface facing inwardly toward the processing space and a second surface facing outwardly away from the processing space, the second surface having a groove, and wherein the apparatus further comprises an auxiliary electrode carried in the groove of the second surface.

54-56. (Cancelled)